Electronic Pater	nt App	olication Fee	Transmi	ttal			
Application Number:	10	10586788					
Filing Date:	02	02-Sep-2008					
Title of Invention:		Plasma Excited Chemical Vapor Deposition Method Silicon/Oxygen/ Nitrogen-Containing-Material and Layered Assembly					
First Named Inventor/Applicant Name:	Zv	Zvonimir Gabric					
Filer:	Ira	Ira Stuart Matsil/Sherry Colgrove					
Attorney Docket Number:	20	2006 VJ 33543 US					
Filed as Large Entity							
U.S. National Stage under 35 USC 371 Fili	ng Fee	s					
Description		Fee Code	Quantity	Amount	Sub-Total in USD(\$)		
Basic Filing:			II				
Pages:							
Claims:							
Miscellaneous-Filing:							
Petition:							
Patent-Appeals-and-Interference:							
Post-Allowance-and-Post-Issuance:							
Extension-of-Time:							

Description	Fee Code	Quantity	Amount	Sub-Total in USD(\$)
Miscellaneous:				
Submission- Information Disclosure Stmt	1806	1	180	180
	Tot	180		